OIPE MAP43
APR 10 2006
PATENT & TRADEMARK OFFICE

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Im-soo PARK, et al	Art Unit: 1746
Serial No.: 10/685,515	Examiner: Saeed T. Chaudhry
Filed: October 16, 2003	*Confirmation No.: 8169*
For: APPARATUS FOR CLEANING SEMICONDUCTOR WAFER INCLUDING HEATING USING A LIGHT SOURCE AND METHOD FOR CLEANING WAFER USING THE SAME (AS AMENDED)	Attorney Docket No.: 249/255 DIV

AMENDMENT UNDER 37 C.F.R. § 1.114

Mail Stop: Amendments
Commissioner for Patents
United States Patent and Trademark Office
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INTRODUCTORY COMMENTS

In connection with the Request for Continued Examination filed concurrently herewith, the following amendments and remarks are respectfully submitted in connection with the above-identified application:

Amendments to the Claims are reflected in a listing of claims, which begins on page 2 of this paper.

Remarks begin on page 4 of this paper.